

IN THE DRAWINGS:

Please amend Figures 1, 2 and 6 as shown on the attached sheets, including formal replacement sheets and annotated sheets showing the changes made. In Figure 1 several terms are replaced with other terms having similar meaning, but which constitute more idiomatic English. In Figure 2, "near infrared" is replaced with --- NIR ---. In Figure 3 "Secondary-differential" is replaced with --- Second differential --- and --- Value of difference spectrum --- is added as a definition of the values indicated at the right vertical side of the chart.

REMARKS

Upon entry of the present Preliminary Amendment-A the claims in the application remain claims 1-4, of which claim 1 is independent.

Several terms and phrases in the title, specification, claims, drawings and abstract are amended by replacement with alternative terms and phrases having corresponding meaning, but which constitute a more accurate translation of International Application PCT/JP2005/003517 and constitute more idiomatic English. Again, in Figure 1 several terms are replaced with other terms having similar meaning, but which constitute more idiomatic English. In Figure 2, "near infrared" is replaced with --- NIR ---. In Figure 3 "Secondary-differential" is replaced with --- Second differential --- and --- Value of difference spectrum --- is added as a definition of the values indicated at the right vertical side of the chart.

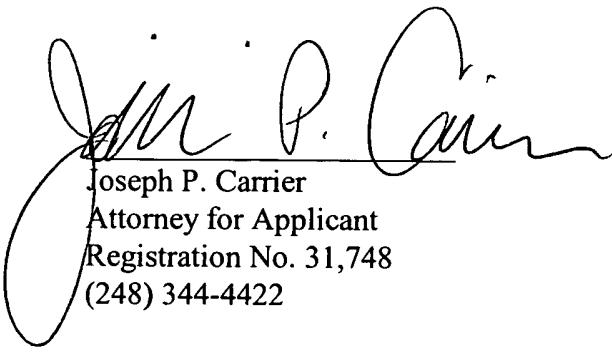
The amendments to the title, specification, and abstract are incorporated in a substitute specification being filed concurrently herewith. Pursuant to 37 CFR 1.125, applicant encloses herewith a clean version of the substitute specification, a marked up copy of the specification showing the changes made thereto, and a verified statement by the undersigned attorney attesting to the fact that no new matter is introduced by the substitute specification.

Applicant respectfully submits that all of the above amendments are fully supported by the original application. Applicant also respectfully submits that the above amendments do not introduce any new matter into the application.

Favorable consideration is respectfully requested.

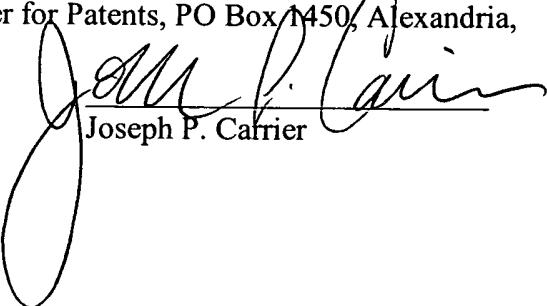
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CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450 on October 18, 2006.


Joseph P. Carrier

KNJ-235-A

METHOD FOR LEVELING STANDARIZING SYSTEM RESPONSE

CHARACTERISTICS OF SPECTROSCOPE SPECTROPHOTOMETER

DESCRIPTION

Cross-reference To Related Applications

[000.1] The present application is the US National Phase of International Application PCT/JP2005/003517, which in turn claims convention priority from Japanese patent application 2004-058443, filed 03 March 2004. The entire disclosures of the referenced International and Japanese priority documents are incorporated herein by reference.

Technical Field

[0001] The present invention relates to a method for leveling a spectroscope standardizing system response characteristic for correcting of a spectrophotometer in order to correct the difference between spectroscope response characteristics spectrophotometric differences generated due to the difference between in response characteristics of a light source, spectrograph wavelength selector, and sensor.

Background Art

[0002] To control measurement errors and fluctuations of generated by a plurality of inspection instruments for mass in large scale production of products, if the adjustment to fit each instrument is frequently performed to adjust each inspection instrument by using an exclusive jig tool. However, in the case of calibration of when

many check points are present to calibrate the inspection instruments, lots of work times and predetermined man-hours are required ~~when many check points are present~~ and finally, the adjustment cost greatly influences a product price. Therefore, it is preferable to minimize the number of check points ~~requiring adjustment~~ to calibrate the instrument. However, in the case of a product for which accuracy of inspection instrument is requested, artifice is necessary.

[0003] For example, Patent Document 1 describes the following expression as a ~~relative relational expression for showing the correlation~~ relationship between the ~~measured value and the true value of a reproduced signal on an optical disk and the measured signal produced by an optical disk inspection instrument~~ in order to reproduce an optical disk ~~to be inspected by an optical disk with similar signal using multi-inspection instruments~~.

True value Y_i =Gain correction coefficient $a_i \times$ measured value X_i +offset correction coefficient b_i (a)

X_i : Measured value of reproduced signal

Y_i : True value of reproduced signal

a_i : Gain correction coefficient for correcting gain for each interval

b_i : Offset correction coefficient for correcting offset for each interval

Moreover, ~~the~~The gain correction coefficient a_i and the offset coefficient b_i are obtained for each interval. Furthermore, Patent Document 1 describes a method for calibrating ~~measurement mean~~each optical disk inspection instrument in accordance with ~~[[a-]]~~ the calibrated ~~value~~values obtained by using the computing means and expression (a). Furthermore, Patent Document 1 describes a method for inspecting an optical disk to be inspected is described in Patent Document 1 using calibrated inspection instruments

Patent Document 1: Japanese Patent Application Publication No.
2003-1897440

DisclosureSummary of the Invention

[0004] However, when an object to be inspected has a frequency (wavelength) ~~characteristic~~~~response~~ more complex than that of an optical disk ~~and the reflection, for example,~~ spectrum of an apple is measured in a wavelength range of 700 to 1,100 nm by using, ~~for example,~~ a ~~discretedispersive~~-type near infrared apparatus~~instrument~~, there is a problem that individual difference between objects to be measured is large, ~~which is not present~~ ~~than that presented~~ in an optical disk.

Though the approximate expression (a) shown in Patent Document 1 is used, it is impossible to find a proper linear correction parameter as shown by linear correction data in Table 1.

Also when using the following approximate expression (b) using a more-complex polynomial,

$$y = k_0 + k_1 s + k_2 x^2 \quad (b)$$

it is impossible to find a proper polynomial parameter as shown by the polynomial correction data in Table 1.

[0005]—

[Table 1]

Adjustment line-condition	Calibration method	
	MLR	PLS

	SEP	Bias	SEP	Bias
No adjustment	0.34	-0.42	0.35	-0.53
700-1,100 nm linear correction	0.34	-1.07	0.32	-1.31
700-1,100 nm polynomial correction	0.34	-0.48	0.31	-1.14
850-1,050 nm linear correction	0.34	-0.46	0.32	-1.24
850-1,050 nm polynomial correction	0.34	0.25	0.31	-1.06

(Note 1) Analysis algorithm

MLR (Multiple Linear Regression)

PLS (Partial Least Squares)

(Note 2)

SEP: Residual-error standard error (~~Standard error of bias~~Bias-corrected expected value)standard error of prediction)

Bias: Average of differences between ~~estimated values and chemical analysis~~
~~actual values according to chemical analysis and estimated values according to~~ near infrared spectroscopy

[0006] Moreover, when moving a calibration model (hereafter referred to as model) for performing quantitative analysis and qualitative analysis by using the near infrared spectroscopy from a unit developing the model to another similar unit, an error occurs due to the difference between ~~spectral apparatus response~~
~~characteristics~~spectrophotometric system responses. In the case of the quantitative analysis, there is a method referred to as bias correction method of the model as a correction method. However, this method is ~~correction of to correct~~ an estimated result, which requires correction for each model and labor and whose operation is complicated.

However, the correction method for qualitative analysis is not developed yet.

[0007] It is an object of the present invention to provide a method for leveling response characteristics—standardizing system response of a spectroscopic~~spectrophotometer~~ for correcting the distortion of a spectrum generated due to the difference between spectroscopic response characteristics system responses of spectrophotometers so that a model developed by a parent~~master~~ unit can be used by a child~~slave~~ unit.

To achieve the above object, a method of the present invention for leveling~~standardizing~~ the system response characteristic of a spectroscopic ~~provides a method for~~spectrophotometer involves adjusting the system response characteristic of a child~~slave~~ unit to the system response characteristic of a parent~~master~~ unit by subtracting the spectrum of a standard substance measured by the parent unit, for example, secondary differential spectrum from the spectrum of the standard substance measured by the child unit, for example, secondary differential spectrum thereby obtaining the difference spectrum between the child unit and the parent unit, and thereby subtracting the difference spectrum from the secondary differential spectrum of each sample to be measured by the child unit. calculating the difference spectrum between the slave unit and the master unit. For example, the difference spectrum may be calculated by subtracting a spectrum of a standard material, for example, a second derivative spectrum, measured by the slave unit, ~~for~~ from a second derivative spectrum of a standard material measured by the master unit. Then the spectrum of each object measured by the slave unit is standardized by subtracting with the calculated difference spectrum. By using the secondary differential~~second derivative~~ spectrum for calculating the difference spectrum, there is an advantage that the baseline shift of the base line is eliminated.

[0008] As the spectrum of the standard substancematerial, the spectrum of a sample to be measured, secondary differentialsecond derivative spectrum, or average spectrum of the spectrum of the sample and the secondary differential spectrumthose spectra mentioned before is considered. In the case of the average spectrum, the following two cases are assumed: a case of measuring a plurality of spectrumspectra by one sample to be measured and obtaining the average spectrum and a case of measuring a plurality of spectrumspectra by a plurality of samples and obtaining the average spectrum.

[0009] An apparatusapparatusinstruments to which near infrared spectroscopy is applied is constituted of a beam of light, spectrograph, light source, spectrographwavelength selector, and sensor. Wavelength characteristics, luminancelight intensity, and sensor sensitivities of themthemspectrophotometer are delicately different for each individual piecepieceinstrument and the combination of spectroscoperesponsecharacteristic which isthese responses gives the overall characteristic of the instrument which isapparatus is delicately different for each apparatus. Moreoverdelicately different for each instruments. MoreoverIn addition, a shift of the wavelength of aspectroscopespectroscopebetween each spectrophotometer occurs. However, the spectroscoperesponsecharacteristic is peculiar to each apparatuscharacteristicsspectrophotometric system response is peculiarspecific to each apparatusinstrument when a light source, spectrographwavelength selector, and sensor are decided.

[0010] Therefore, because a shift of absorbance value of a childchildslave unit in each wavelength from a parentparentmaster unit similarly occurs in each sample to be measured, it is possible to correct a spectrum distortion generated due to the difference between spectroscoperesponsecharacteristicscharacteristicsspectrophotometric system responses by subtracting the shift of the absorbance value in each wavelength

from the spectrum of each sample, for example, secondary differential derivative spectrum.

[0011] According to By using the present invention, in the case of a fruit sugar content selector; sweetness sorting machine, it is easy to move a sugar content analytical distillation developed by a reference selection line (parent unit) transfer a mathematical model to predict sweetness developed from spectra of a master unit to a plurality of other selection lines (child unit); sweetness sorting units (slave units). By this invention, the difference between lines is eliminated, and the reliability of the selector; sweetness sorting machine is improved. Moreover, there are advantages that the selector; sweetness sorting machine is easily maintained and persons are released from the hard work at the job site for correcting the difference between lines. by the conventional bias-correction technique.

Brief Description of the Drawings

[0012] Figure 1 is an illustration showing an example of an apple sugar content selector; sweetness sorting machine;

Figures 2(a) and 2(b) are illustrations showing secondary differential spectra measured by near infrared apparatuses (near infrared apparatuses NIR) instruments A and B;

Figure 3 is an illustration showing an example of applying a model developed by the near infrared apparatus NIR instrument A to the spectrum of the near infrared apparatus NIR instrument B;

Figure 4 is an illustration showing a difference spectrum obtained by subtracting the secondary differential spectrum of an apple

measured by the ~~near infrared apparatus~~NIR instrument A from that of an apple measured by the ~~near infrared apparatus~~NIR instrument B;

Figure 5 is an illustration showing an example of applying a model developed by the ~~near infrared apparatus~~NIR instrument A to the ~~leveling spectrum~~standardized spectra of the ~~near infrared apparatus~~NIR instrument B; and

Figure 6 is an illustration showing a difference spectrum obtained by subtracting the average spectrum of ~~secondary differential spectra~~derivative spectra measured by a ~~parent~~parent~~master~~unit from the average spectrum of ~~secondary differential spectra~~derivative spectra measured by a ~~child~~child~~slave~~unit and the average spectrum of the ~~parent~~parent~~master~~unit.

Best Mode for Carrying Out Detailed Description of the Invention

[0013] ~~Best~~A best mode for carrying out the invention is described below. Figure 1 is one of the embodiments of the present invention, which shows an example of an apple ~~sugar content selector~~sweetness sorting machine. In the case of the ~~selector~~sweetness sorting machine, a tungsten lamp is used for the light source, a diffraction grating is used for the ~~spectrograph~~wavelength selector, and a diode array detector is used for the sensor.

[0014] At the stage for preparing a model by the ~~parent~~parent~~master~~unit in Figure 1(1), a plurality of samples (apples) 1 to be measured are measured by the sensor 2 of the ~~parent~~parent~~master~~unit to obtain the ~~secondary differential spectrum~~derivative spectrum 3 of the ~~parent~~parent~~master~~unit. Then, chemical analysis values 4 of the samples (apples) 1 are obtained. A model 5 is obtained by the chemometrics method such as the multiple regression analysis in

accordance with with based on the data for the above secondary differential derivative spectrum 3 and the above chemical component values 4.

[0015] At the stage for obtaining the difference between spectral characteristics of the parentparentmaster unit and chilchilslave unit in Figure 1(2), a plurality of samples (apples) 6 to be measured are measured by the sensor 2 of the parentparentmaster unit to obtain the average spectrum of the secondary differential spectrums derivative spectra of the parentparentmaster unit. Then, the same samples (apples) 6 to be measured are measured by the sensor 8 of the chilchilslave unit to obtain the average spectrum 9 of the secondary differential spectrums derivative spectra of the chilchilslave unit. Moreover, the difference spectrum 10 between secondary differential values of second derivative values is obtained by subtracting the average spectrum 7 of the parentparentmaster unit from the average spectrum 9 of the chilchilslave unit.

At the stage for leveling leveling standardizing the spectral characteristics of the chilchilslave unit in Figure 1(3), each sample (apple) 11 to be measured is measured by the sensor 8 of the chilchilslave unit and the secondary differential derivative spectrum 12 of the chilchilslave unit is measured to obtain a leveled leveled standardized secondary differential derivative spectrum 13 obtained by subtracting the difference spectrum 10 from the secondary differential derivative spectrum 12. By applying the model 5 to the leveled leveled standardized secondary differential derivative spectrum 13, a purposed chemical component value 14 is obtained.

[0016] Figure 2 is is shows near infrared secondary differential spectrums derivative spectra of apples (product class variety: Fuji) measured by two discrete dispersive-type near infrared apparatuses apparatuses instruments (NIRS6500 made by NIR SystemsNIR, Systems, NIRS6500) (referred to as near infrared

apparatuses ~~apparatuses~~ NIR instruments A and B). The near infrared ~~apparatus~~ instrument uses a tungsten lamp as a light source, a diffraction grating as a ~~spectrograph~~ wavelength selector, and a silicon detector as a sensor.

[0017] The ~~following~~ model of the following expression is developed ~~through~~ by multiple regression ~~in accordance with~~ with ~~based on~~ the ~~secondary~~ differential derivative values ~~measured by the NIR instrument A~~ and sugar contents (Brix values) of ~~spectrums~~ spectra of 100 apples, ~~measured by the near infrared apparatus A~~.

$$C = 16.035 - 266.386D2A(906) + 1351.578D2A(870)$$

... (1)

~~In this case~~ Where, C ~~denotes~~ is a Brix value, and D2A(906) and D2A(870) are ~~secondary~~ differential derivative values of ~~spectrum~~ spectra at 906 nm and 870 nm, respectively.

[0018] Figure 3 shows results of applying the model of the above expression (1) to a spectrum measured by the ~~near infrared~~ apparatus ~~apparatus~~ NIR instrument B. In this case, it is found that a negative bias of -0.42° Brix is generated.

[0019] Figure 4 is a difference spectrum obtained by subtracting the average spectrum of the ~~near infrared~~ apparatus A from the average spectrum of ~~secondary~~ differential ~~spectrums~~ second derivative spectra of the above 100 apples ~~measured by the near infrared~~ apparatus ~~apparatus~~ NIR instrument A from the average spectrum of ~~secondary~~ differential ~~spectrums~~ derivative spectra of the above 100 apples ~~same samples measured by the near infrared~~ apparatus ~~apparatus~~ NIR instrument B.

Figure 4 shows the wavelength range of 860 to 910 nm to be used for the model. It is found that the ~~secondary~~ differential derivative value of the ~~near infrared~~

~~apparatus~~NIR instrument B is slightly larger than that of the ~~near infrared~~
~~apparatus~~NIR instrument A in the wavelength region. At 906 nm, the
secondary differential derivative value is ~~large~~larger by 0.0021515 and at 870 nm, the
value is large by 0.0008103. Therefore, when assuming that the secondary differential
derivative values at 906 nm and 870 nm of the ~~near infrared~~NIR
instrument B are $D2A(906)_B$, and $D2A(870)_B$, respectively, a corrected value is
obtained from the following expression.

$$D2A(906) = D2A(906)_B - 0.0021515$$

$$D2A(870) = D2A(870)_B - 0.0008103 \quad \dots (2)$$

By substituting the value of expression (2) for the model of expression (1), it is
possible to apply the model developed by the ~~near infrared~~NIR
instrument A to the spectrum measured by the ~~near infrared~~NIR
instrument B.

[0020] Figure 5 shows results of correcting and recalculating the data shown in
Figure 3 by the above described method. A bias becomes 0.05° Brix and occurrence of
errors produced due to the difference between ~~specroscopic response~~
~~characteristics~~characteristicssystem responses of spectrophotometers is almost
cancelled. This improvement degree is clear as a result of comparing with calibration
result data of linear correction and polynomial ~~expression~~ correction in Table 1.

[0021] Figure 6 shows a difference spectrum obtained by subtracting the average
spectrum of ~~secondary differential spectrums~~derivative spectra measured by the
~~parent~~parentmaster unit from the average spectrum of ~~secondary differential spectrum~~
derivative spectra measured by the ~~child~~childslave unit and the average spectrum of
the ~~parent~~parentmaster unit in a wavelength region of 850 to 1,050 nm together. When
assuming a difference spectrum as $\Delta A(\lambda)$ and a ~~secondary differential derivative~~

spectrum of each a sample measured by the ~~ehildehildslave~~ unit as $S_B(\lambda)$, a ~~leveledleveledstandardized~~ secondary ~~differential~~ derivative spectrum $S_C(\lambda)$ is shown by the following expression.

$$S_C(\lambda) = S_B(\lambda) - \Delta A(\lambda) \quad \dots (3)$$

In this case, λ denotes Where, λ denotes is a wavelength (nm).

Industrial Applicability

[0022] It is possible to apply ~~leveling of the spectroscope response characteristic~~ the standardization method for standardizing of system response of spectrophotometer by the present invention to a line for measuring, for example, a sweetness sorting machine which measures the spectrum of fruit moved by, for example, a belt conveyer and selecting selectsing the fruit in accordance with a ~~chemical component value such as an obtained sugar content~~.

[0023] Although there have been described what are the present exemplary embodiments of the invention, it will be understood that variations and modifications may be made thereto within the spirit and scope of the appended claims.

ABSTRACT

A method for leveling spectroscope response characteristicsstandardizing system response of spectrophotometer which corrects the difference between spectroscope response characteristicsspectrophotometric system responses generated due to the difference betweenin response characteristics of a light source, spectrometerwavelength selector, and sensor, and involves obtaining the difference spectrum between a parentmaster unit and a childslave unit relative to a standard substancematerial and adjustingstandardizing the response characteristic of the childslave unit to the response characteristic of the parentmaster unit by subtracting the difference spectrum from the spectrum of each sample to be measured by the childslave unit. With an apparatusapparatusinstrument which is constituted of a light source, spectroscopewavelength selector, and sensor and to which a near infraredNIR spectroscopy is applied, a shift of an absorbance value inat each wavelength of the childchildslave unit from the absorbance value of the parentparentmaster unit is similarly generated in each sample to be measured. Therefore, byBy subtracting the shift of the absorbance value at each wavelength from the spectrum of each sample, it is possible to correct the spectrum distortion generated due to the difference between system response characteristics of spectroscopesofspectrophotometer.

FIG. 1

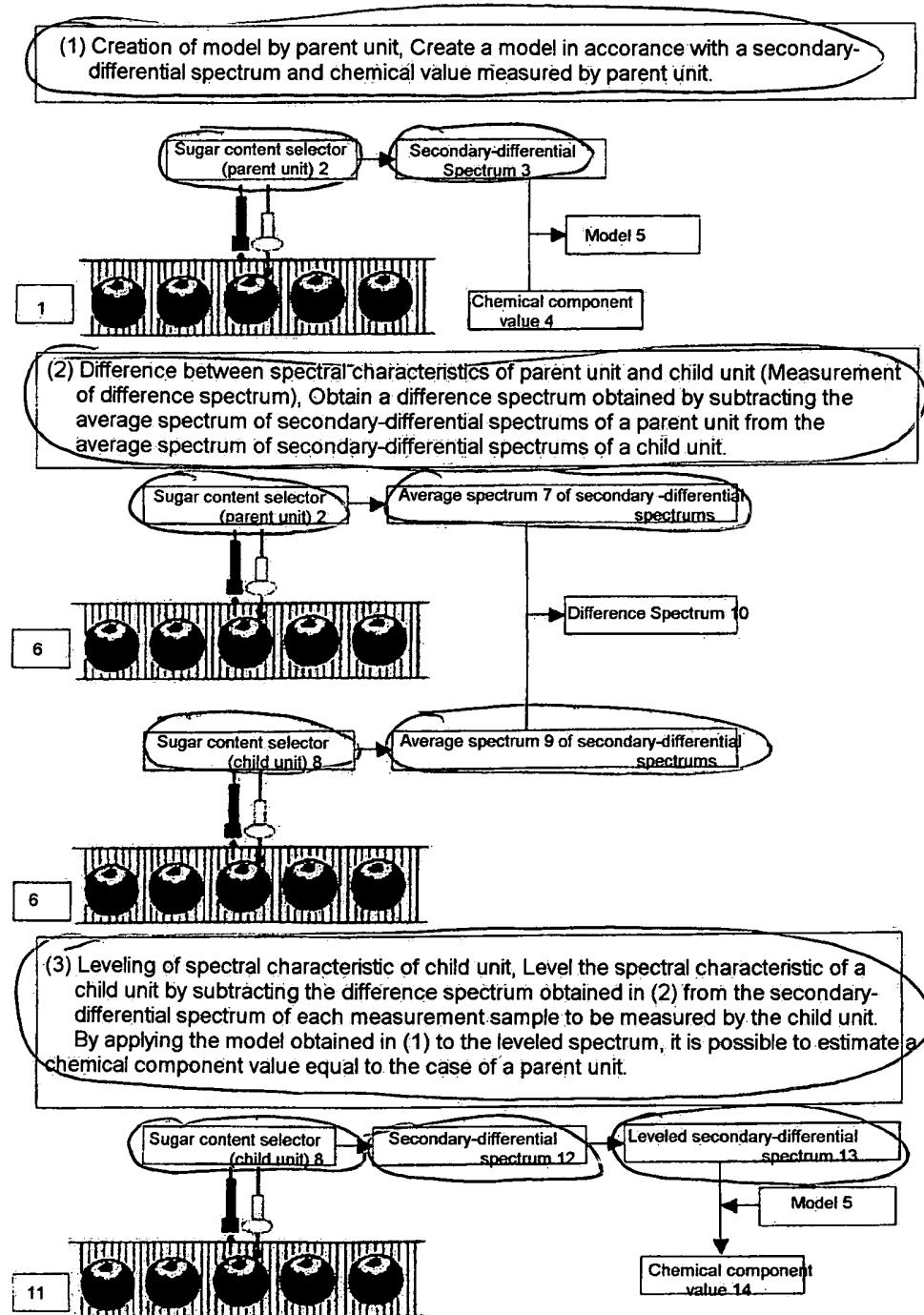


FIG. 2

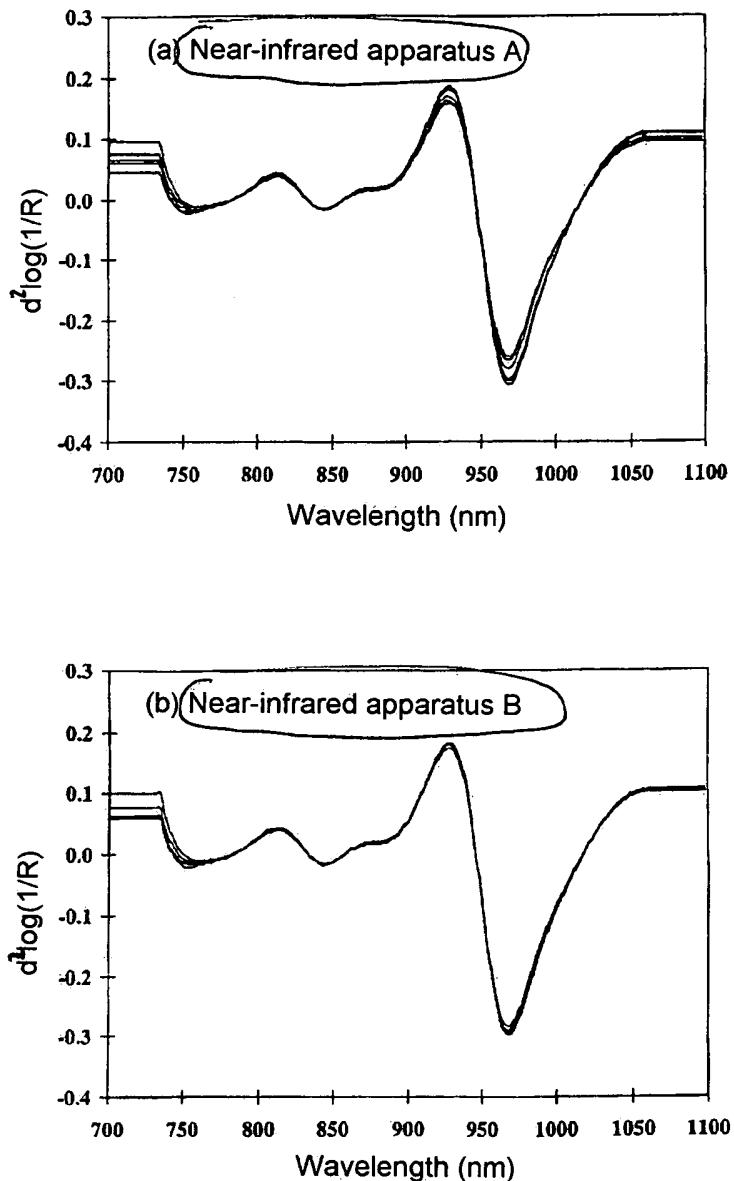


FIG. 3

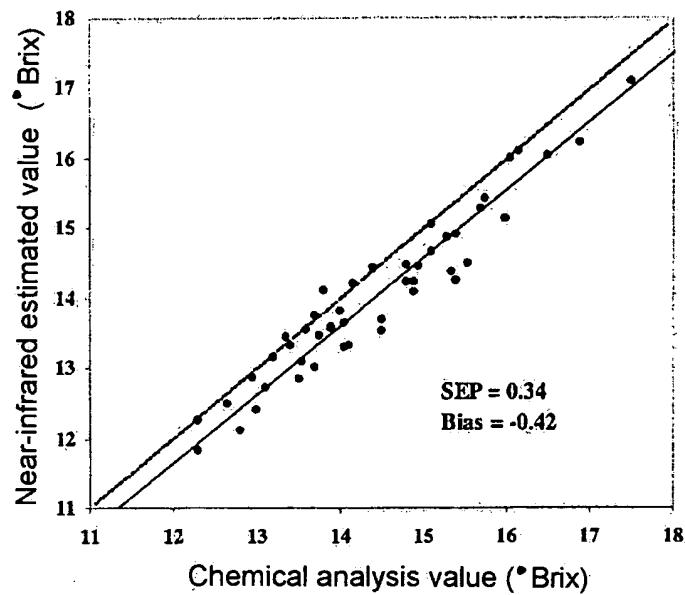


FIG. 4

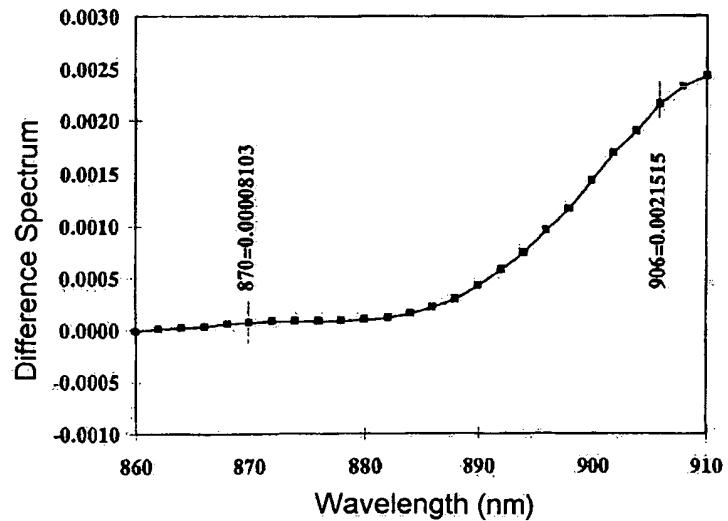


FIG. 5

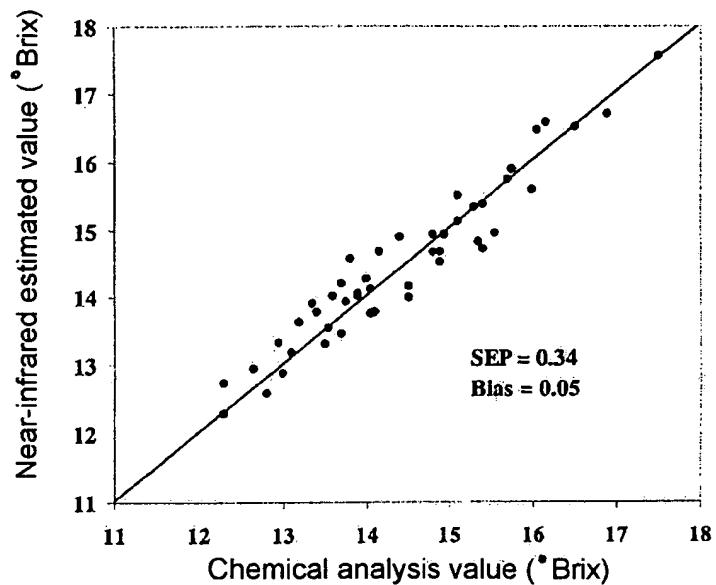


FIG. 6

